Facility Name:	Arglass Yamamura, LLC	Date of Application:	July 2023
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## **FORM 5.00 MONITORING INFORMATION**

Emission Unit/APCD Name	Monitored Parameter		
	Parameter	Units	Monitoring Frequency
CF02/ESP2	Sorbent feed rate setting		Continuous
CF02	Pressure drop	Inches of w.c.	Continuous
CF02/ESP2	NOx		Continuous
	Name CF02/ESP2 CF02	Emission Unit/APCD Name Parameter  CF02/ESP2 Sorbent feed rate setting  CF02 Pressure drop	Emission Unit/APCD Name     Parameter     Units       CF02/ESP2     Sorbent feed rate setting       CF02     Pressure drop     Inches of w.c.

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SO2 will be monitored via sorbent feed rate setting. A continuous emissions monitoring systems	(CEMS)	will be
implemented to monitor NOx emissions.		